

Recipe Parameters for STS etcher & AV etcher

Gases (sccm)	Ar	CHF3	CF4	O2	SF6	Pressure (mT)	Power (watts)
<u>Recipe</u>							
Nit1			40	4		100	100
Nit2			40	4		100	50
Nit3			40	4		100	25
Fastpoly				4	25	100	100
Pjsnitd1	50		40		10	75	150
Slowpoly	5			2	12	40	20
Tyb-test		25	6			50	175
Pjsoxide	50	50	25			75	150
O2-clean				99		100	100